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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 2812  
Examiner: Stanetta D. Isaac

In Re PATENT APPLICATION of:

Applicant(s): Jun KANAMORI

Serial No.: 10/634,851

Filing Date: August 6, 2003

For: SEMICONDUCTOR DEVICE  
FABRICATION METHOD USING  
OXYGEN ION IMPLANTATION

Atty. Dkt.: MAE 292

**REQUEST FOR  
RECONSIDERATION**

\_\_\_\_\_  
August 11, 2005

**Mail Stop Amendment**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

*Please Enter*  
*SDI 8/24/05*

Sir:

Reconsideration of the final rejections presented in the Examiner's Action  
mailed on May 25, 2005, is requested for the following reasons: